

Electronic Patent Application Fee Transmittal

Application Number:	10583976
Filing Date:	
Title of Invention:	Method for setting plasma chamber having an adaptive plasma source, plasma etching method using the same and manufacturing method for adaptive plasma source
First Named Inventor:	Yeong Su Song
Filer:	Sungho Hong/Anita Coughlan
Attorney Docket Number:	4913-0001

Filed as Small Entity

U.S. National Stage under 35 USC 371 Filing Fees

Description	Fee Code	Quantity	Amount	Sub-Total in USD(\$)
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Basic Filing:

Pages:

Claims:

Miscellaneous-Filing:

Oath/decl > 30 mo. from priority date	2617	1	65	65
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Petition:

Patent-Appeals-and-Interference:

Post-Allowance-and-Post-Issuance:

Extension-of-Time:

Description	Fee Code	Quantity	Amount	Sub-Total in USD(\$)
Miscellaneous:				
Total in USD (\$)				65